

## Introduction

The Future TTU Ion beam Facility is developing an optimized ion source to facilitate tests that require ion beams. A critical but small component of such a device is the ion source used to create the ion beam.

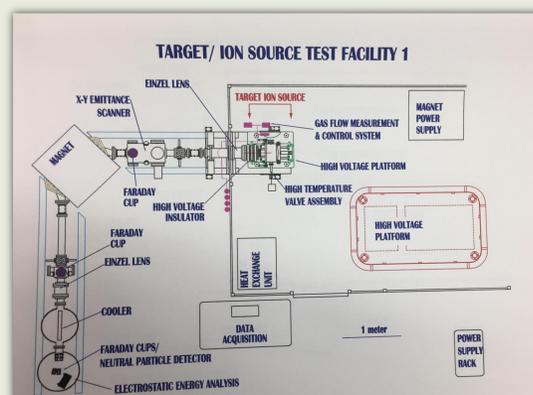


Figure 1: Ion Facility Layout

## How This Works

Ions can be generated via heating, photon excitation (Lasers), and even electric stimulus. Using one of these methods a gas or solid is excited by the added energy and becomes a plasma. The plasma contains ionized atoms and free roaming electrons. These ions can then be manipulated magnetically into a focused shape and propelled as a beam of ions.

## Ion Source Options

Given several choices of Ion generators we will need to select the best fit in terms of cost, complexity, and productiveness. Some promising options include:

- Laser ion source
- Penning ion source
- Sputter ion source

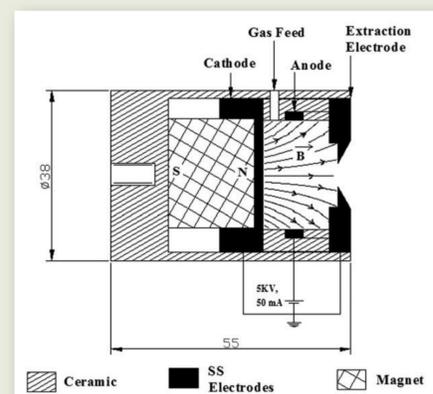


Figure 2: Penning Ion Source General Design Cross-section [1]



Figure 3: Optical Table & Laser

## Conclusion

Using simulation software such as IBSimu[2] we will begin exploring the form of our ion source before we spend our resources. As shown in figure 4 we already have an ion source that we are eager to test in simulation.



Figure 5: High Voltage Platform w/ Proposed Ion Generator in grey

## Ion Source Designs

- Laser Sources use photons to excite a target material into an ionized plasma.
- Sputter Sources use a very hot vapor to "Sputter off" of a target material. This target then releases ions.
- Penning Sources use high voltage and low pressure to release ions from a target material.

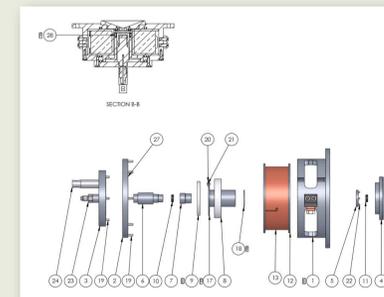


Figure 4: Existing Sputter Ion Source

## References

- [1] Das, B.k., et al. "Development of Hollow Anode Penning Ion Source for Laboratory Application." Nuclear Instruments and Methods in Physics Research Section A:  
[2] Kalvas, Taneli. "IBsimu." Ion Beam Simulator, 1.0.6, SourceForge, 7 Aug. 2015, ibsimu.sourceforge.net/.

